

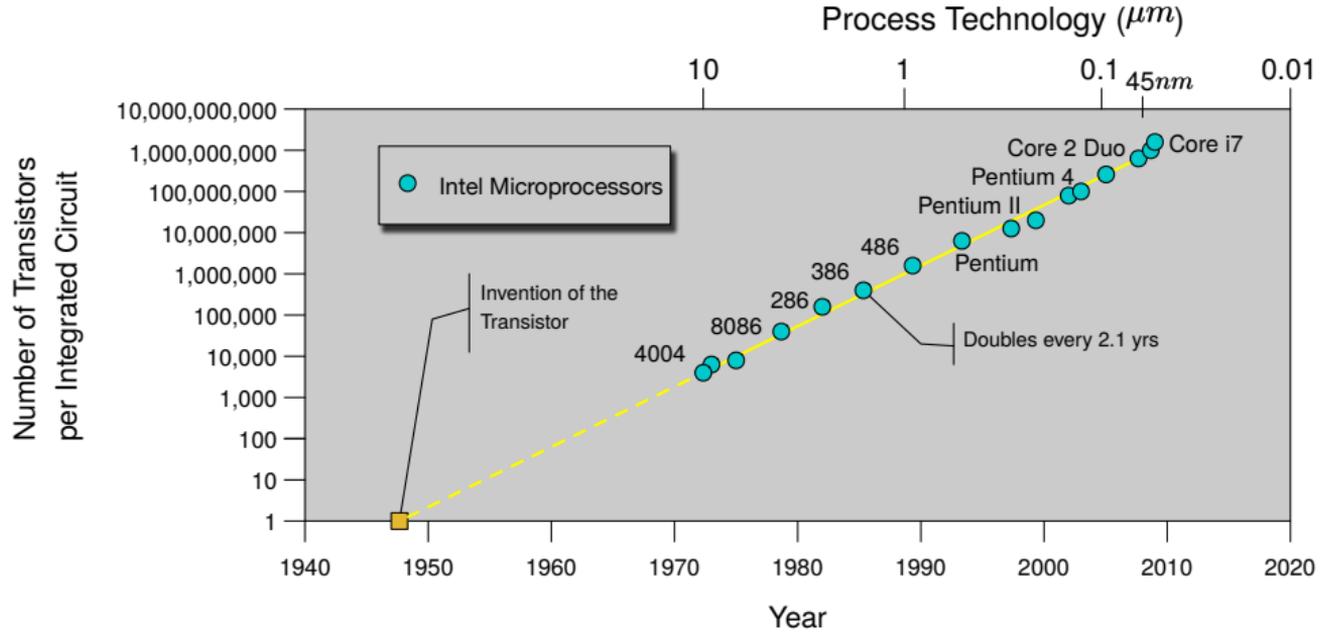
OpenMPL: An Open Source Layout Decomposer

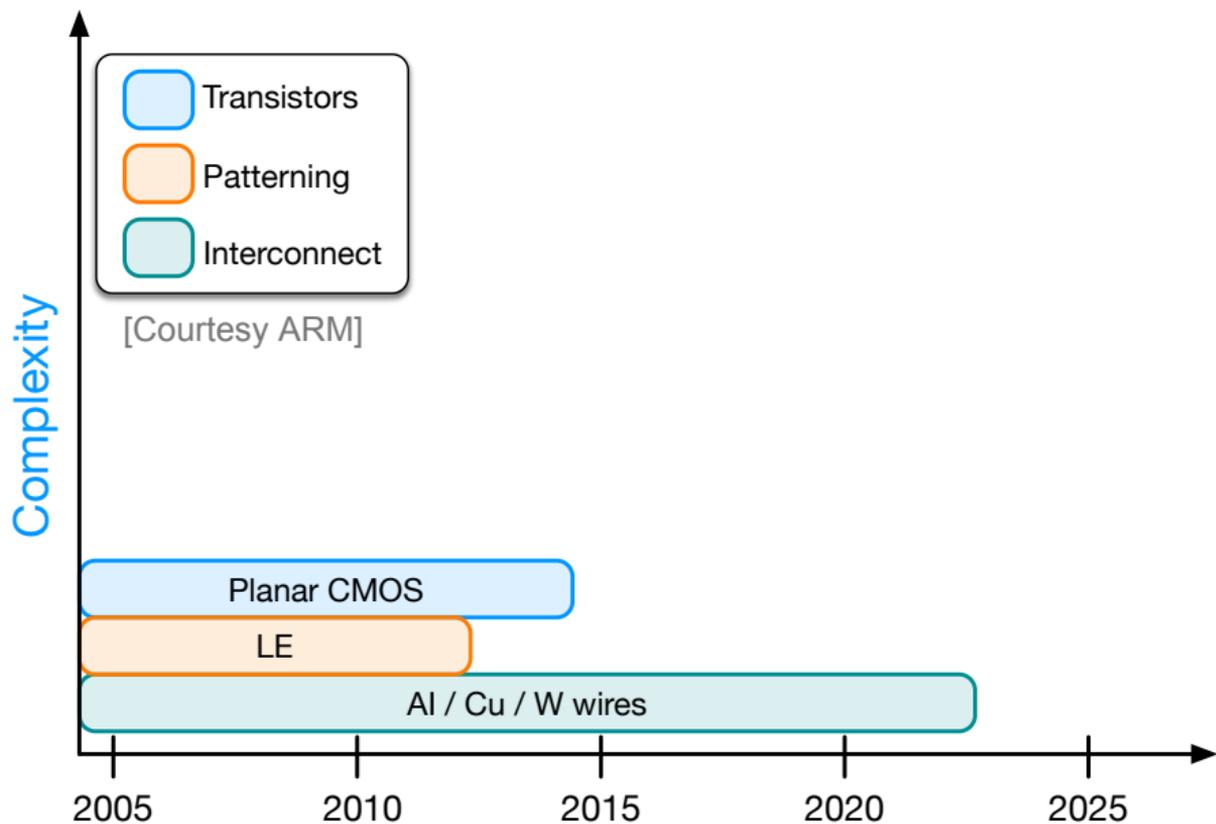
Wei Li¹, Yuzhe Ma¹, Qi Sun¹, **Yibo Lin**², Iris Hui-Ru Jiang³,
Bei Yu¹, David Z. Pan⁴

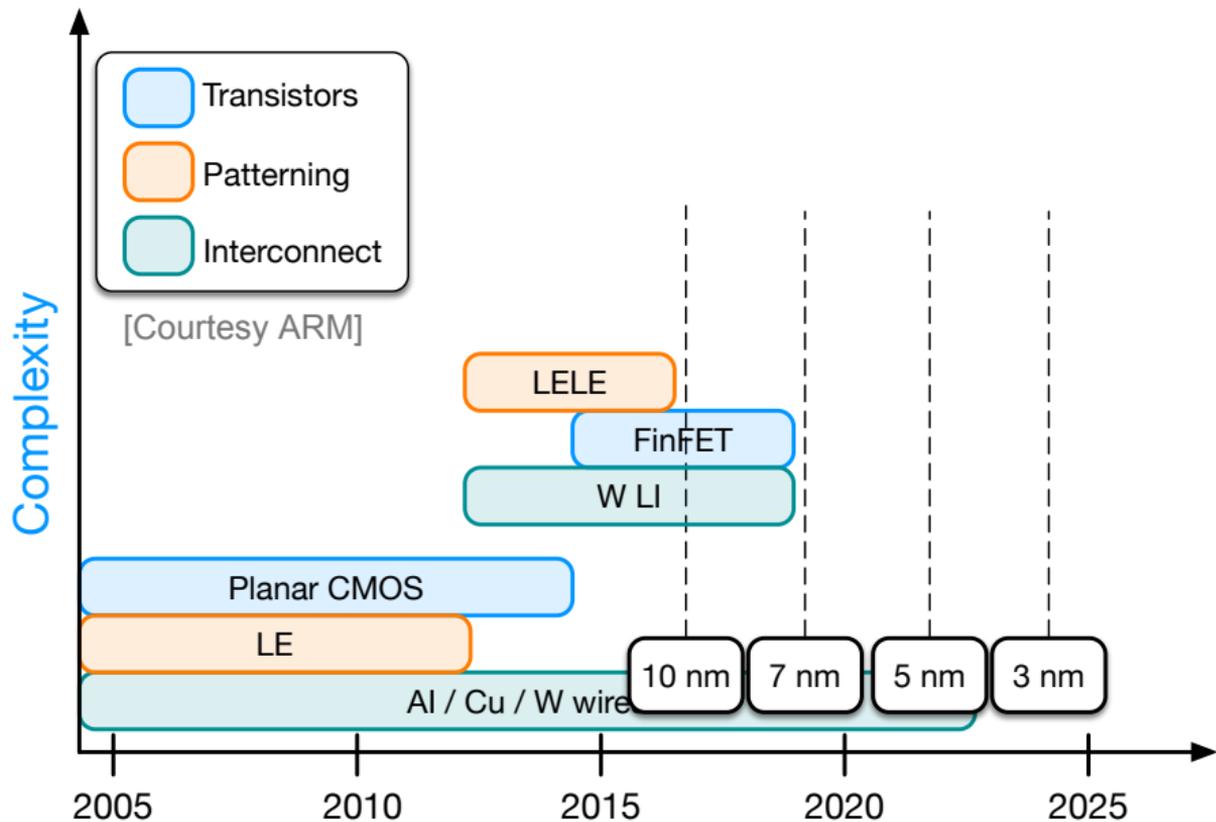
¹The Chinese University of Hong Kong, ²Peking University,
³National Taiwan University, ⁴University of Texas at Austin



Moore's Law



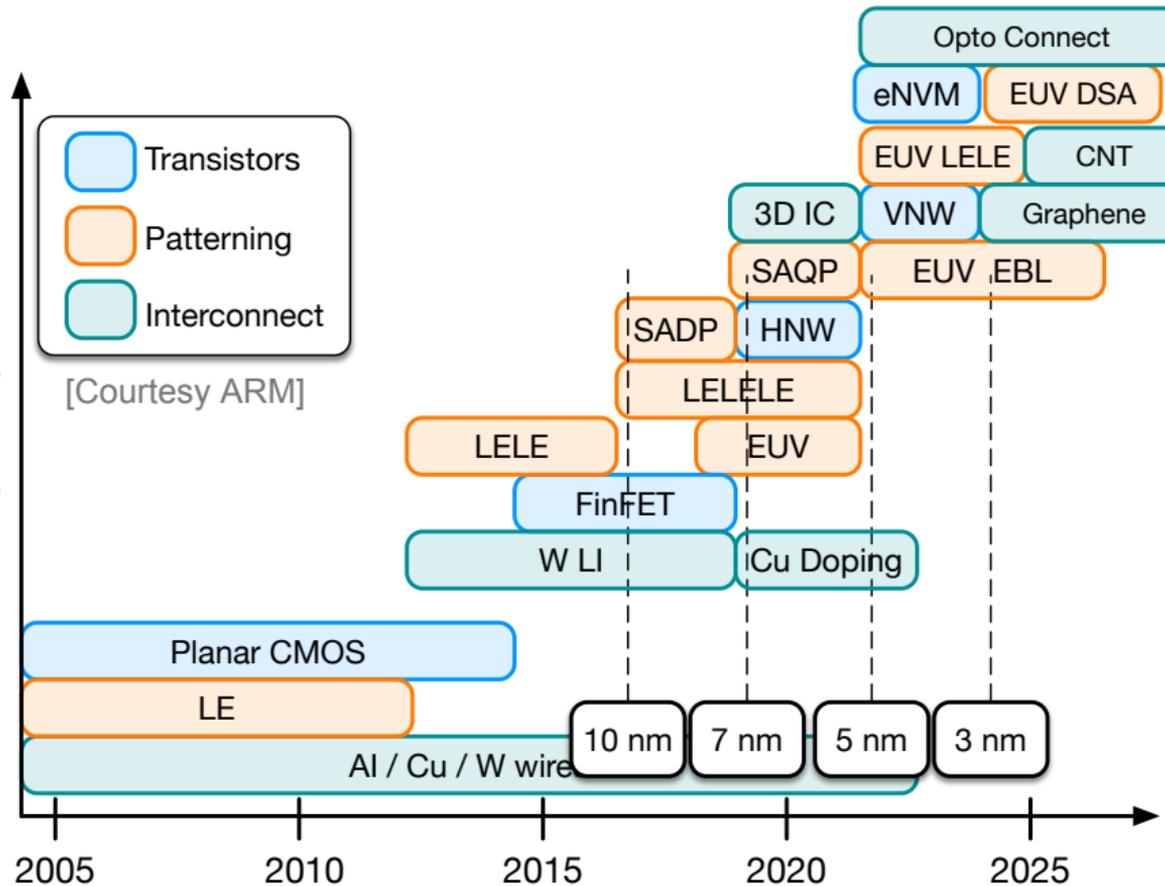




Complexity

- Transistors
- Patterning
- Interconnect

[Courtesy ARM]

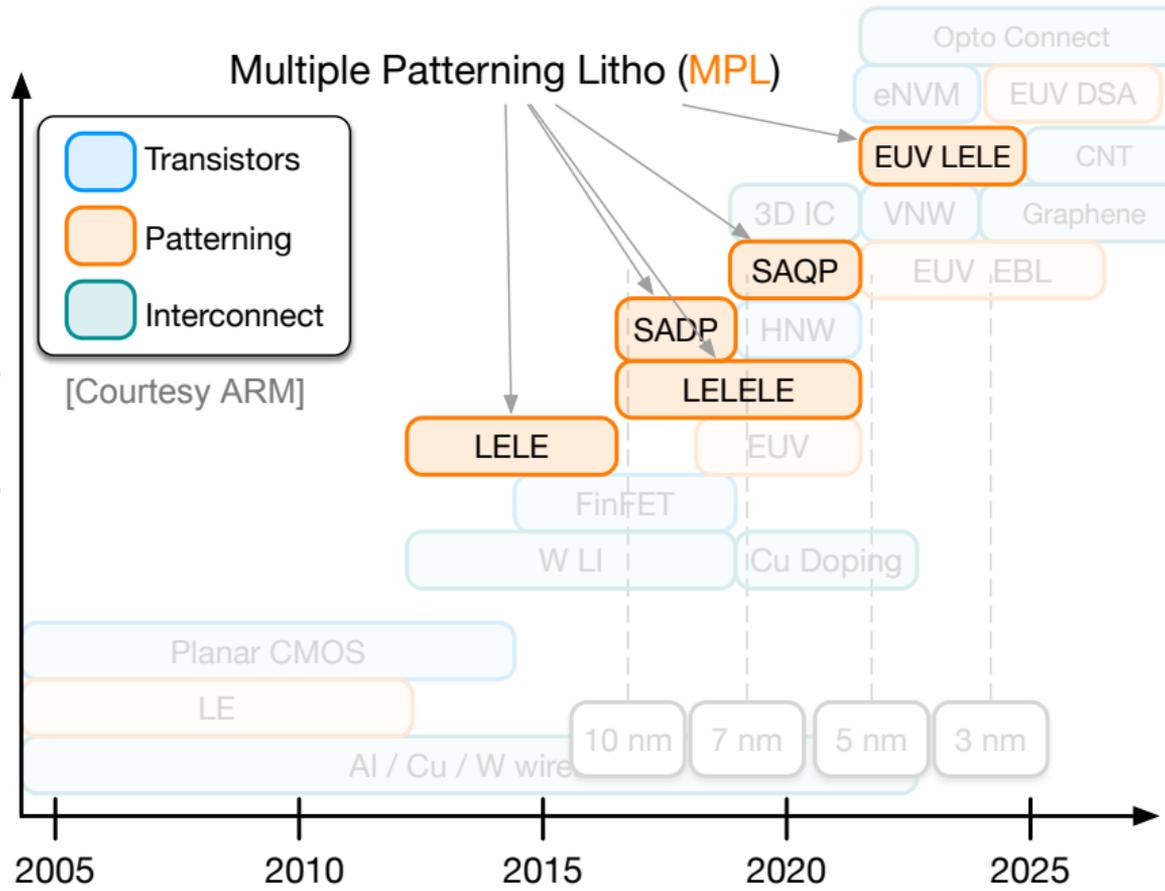


Complexity

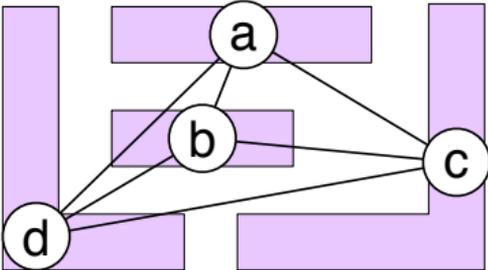
Multiple Patterning Litho (MPL)

- Transistors
- Patterning
- Interconnect

[Courtesy ARM]



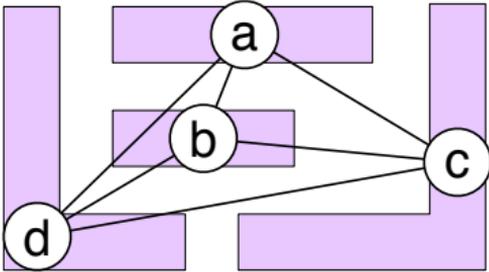
Multiple Patterning Layout Decomposition



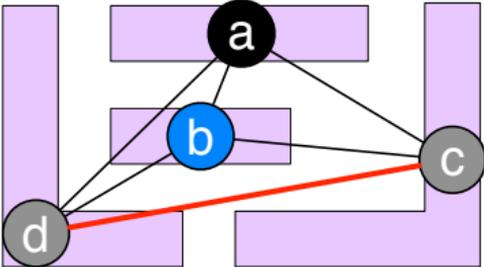
(a) Original layout



Multiple Patterning Layout Decomposition



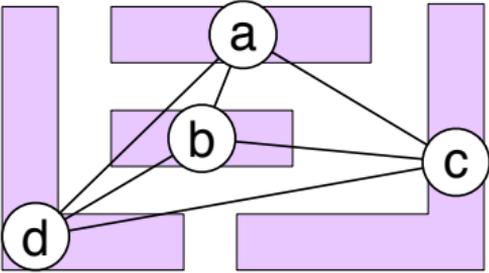
(a) Original layout



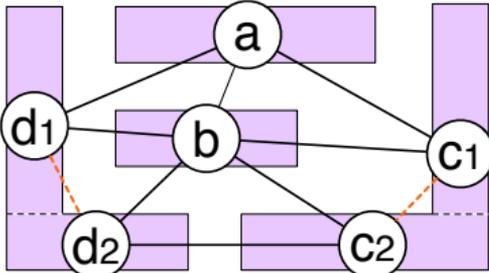
(b) TPL layout with conflicts



Multiple Patterning Layout Decomposition

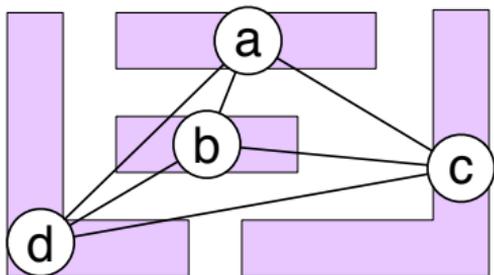


(a) Original layout

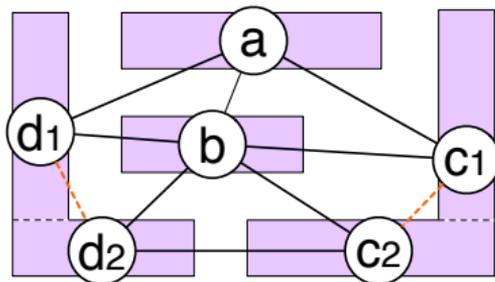


(b) Layout graph

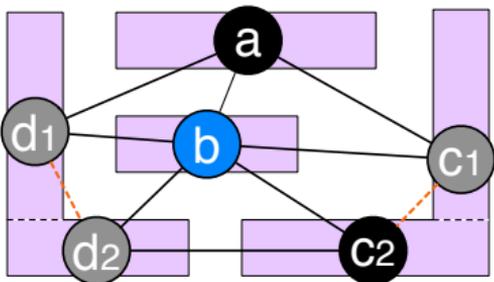
Multiple Patterning Layout Decomposition



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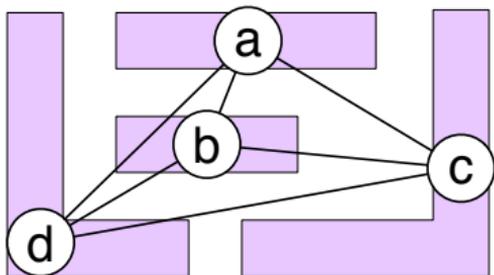
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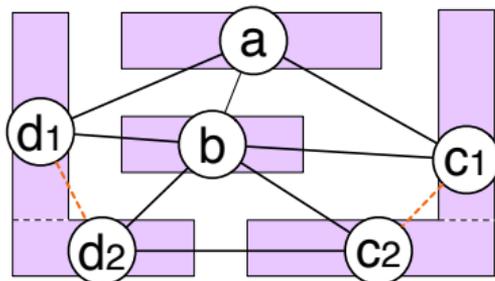
(c) Coloring on layout graph



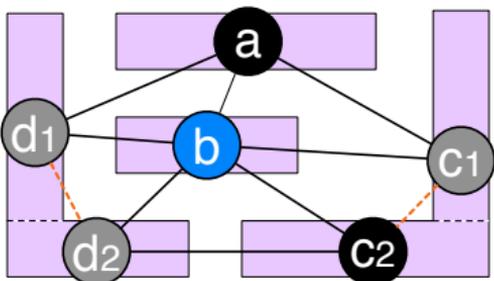
Multiple Patterning Layout Decomposition



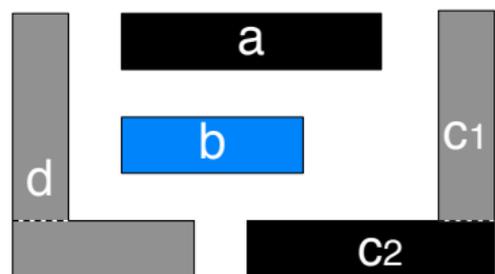
(a) Original layout



(b) Layout graph



(c) Coloring on layout graph

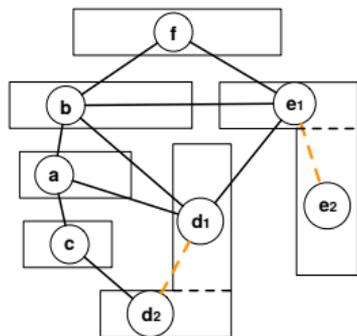


(d) Final decomposed layout



Mathematical Formulation

- ▶ Some conflicts can be solved by **Stitch** Insertion.



k Pattern Layout Decomposition

$$\min_{\mathbf{x}} \sum_{e_{ij} \in CE} c_{ij} + \alpha \times \sum_{e_{ij} \in SE} s_{ij},$$

$$\text{s.t. } c_{ij} = \{x_i == x_j\},$$

$$s_{ij} = \{x_i \neq x_j\},$$

$$x_i \in \{0, 1, \dots, k\},$$

$$\forall e_{ij} \in CE,$$

$$\forall e_{ij} \in SE,$$

$$\forall i \in V.$$

- ▶ x_i is a variable for the k available colors of the pattern v_i .
- ▶ c_{ij} is a binary variable representing conflict edge $e_{ij} \in CE$.
- ▶ s_{ij} stands for stitch edge $e_{ij} \in SE$.

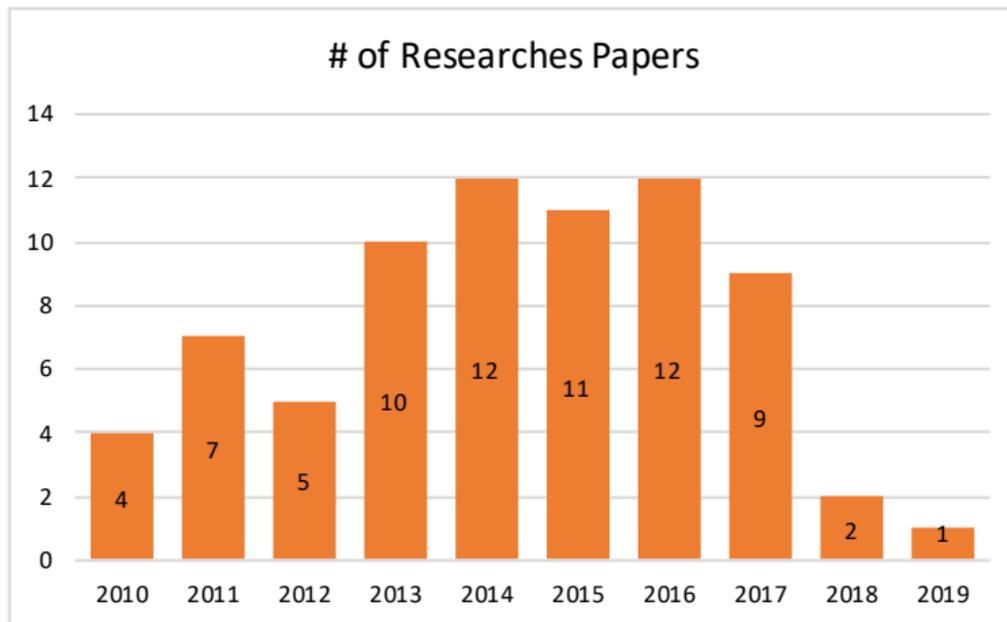


Research Trend for Layout Decomposition

An **UNDERESTIMATION** from Google Scholar

Google Scholar

allintitle: "layout decomposition"



Challenges in Layout Decomposition Research

Complicated workflow and huge development overhead

- ▶ GDSII parsing and writing
- ▶ Layout graph construction and stitch insertion
- ▶ Graph simplification and core solvers



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No consistent framework for fair comparison

- ▶ Different implementations to the same algorithm
- ▶ Hard to make detailed comparison in depth



OpenMPL 2.0: Open-Source Layout Decomposition Tool

limbo018 / OpenMPL

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An open multiple patterning framework Edit

Manage topics

312 commits 6 branches 7 releases 4 contributors BSD-3-Clause

Branch: master New pull request Create new file Upload files Find file Clone or download

limbo018 Merge branch 'develop' Latest commit 0eda4a7 3 minutes ago

bin	prepare for ASICON test	2 days ago
cmake	cmake and submodules in progress	3 months ago
images	add images to readme	3 days ago
erc	remove unused files	4 minutes ago
https://github.com/limbo018/OpenMPL		
.gitignore	stitch with only exactly one	2 months ago
.gitmodules	trial cmake	3 months ago
CMakeLists.txt	fix issue with boost timer and chrono order	3 days ago
LICENSE	Initial commit	last year
Readme.md	prepare for asicon release	4 hours ago
gdb.sh	OpenMPL	last year
run.sh	OpenMPL	last year

Readme.md

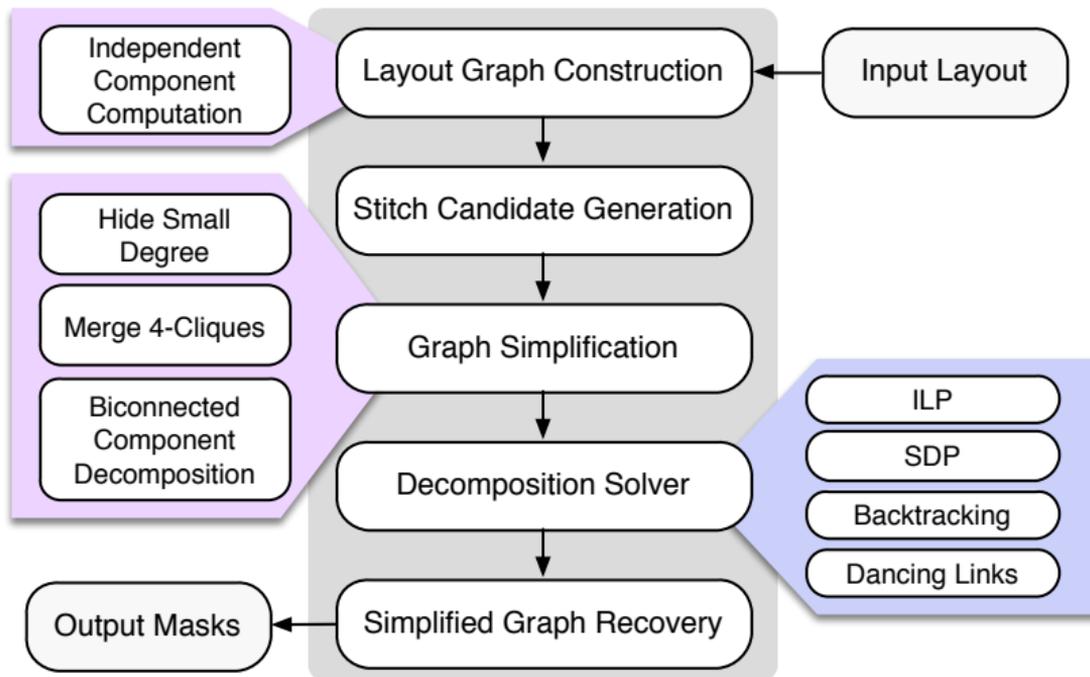
OpenMPL

OpenMPL stands for open multiple patterning lithography framework.

Stitch Insertion	Graph Simplification	Decomposition
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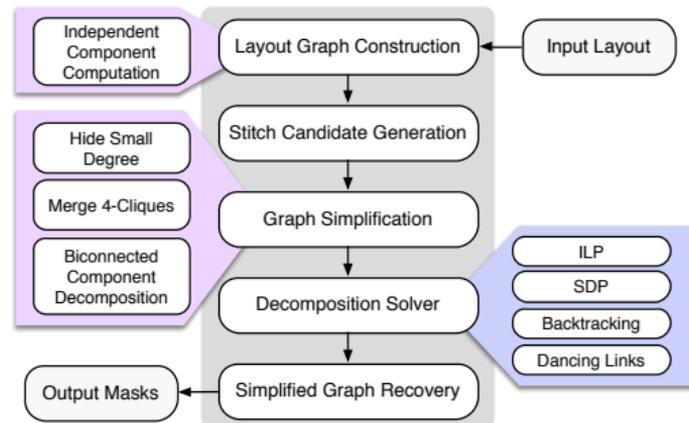


Workflow



Design Principles

- ▶ **Decoupled design stages**
- ▶ **Graphs for communications among kernel stages**
- ▶ **Efficiency and generality for different mask data**



Extensible API to Incorporate New Algorithms

► Create a solver

```
// A solver class
class InstantColoring
    : public Coloring
{
public:
    // g is a boost::graph
    InstantColoring(g);
protected:
    virtual double coloring()
    {
        // override base function
        // return cost
    }
};
```



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    }
};
```

▶ Integrate the solver

```
// define a solver
switch (algorithm)
{
    case BruteForce:
        solver = new BruteForce (g);
    case InstantColoring:
        solver = new InstantColoring (g);
    ...
}
...
// solve coloring
(*solver) ();
```



OpenMPL: Open-Source Layout Decomposition Tool

We implement several layout decomposition solvers.

- ▶ **Backtracking**: Use DFS algorithm to find the solutions [Yu+,ICCAD'13].



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- ▶ **Integer Linear Programming**: Convert the problem into linear programming by binary encoding of vertex colors [Yu+,ICCAD'11].
- ▶ **Dancing Links**: Treat the problem as an exact cover problem and solve it in the BFS style [Chang+,DAC'16].



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We implement several layout decomposition solvers.

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- ▶ **Dancing Links**: Treat the problem as an exact cover problem and solve it in the BFS style [Chang+,DAC'16].
- ▶ **Semidefinite Programming**: Use SDP to relax the problem and solve it in polynomial time [Yu+,ICCAD'11].



Layout Simplification

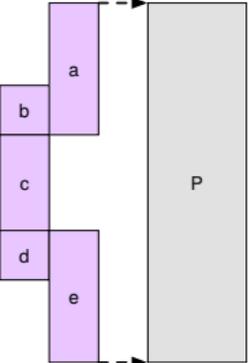
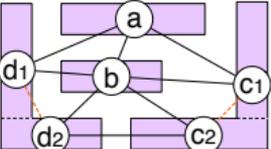
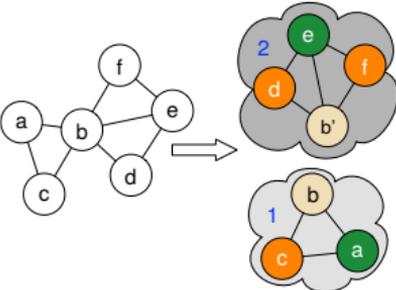
Reduce the graph size and therefore reduce the computation complexity.

- ▶ Level 0: **No Simplification**. Do not conduct any simplification.
- ▶ Level 1: **Hide small degree**. Temporarily remove nodes with low degree [Yu+,TCAD'15] [Lin+,SPIE'16].
- ▶ Level 2: **Merge 4-Clique**. Detect and merge sub-4-clique structures [Lin+,SPIE'16].
- ▶ Level 3: **Biconnected component decomposition**. Partition original graph into independent components [Kahng+,ICCAD'08].



Additional Features

- ▶ **Multithreading:** Solve components in parallel.
- ▶ **Stitch Insertion:** Insert stitches to solve some conflicts.
- ▶ **Shape Friendly:** Specify the shape (POLYGON or RECTANGLE) easily.



Command Line Options

Selected Options	Descriptions
-coloring_distance	a floating point number indicating number of coloring distance in nanometer
-color_num	an integer indicating number of masks (colors) < 3 4 >
-simplify_level	an integer indicating graph simplification level < 0 1 2 3 >
-path_layer	an integer indicating layer for conflict edges
-precolor_layer	an integer indicating layer for pre-colored patterns
-uncolor_layer	an integer indicating layer for coloring
-algo	algorithm type < ILP BACKTRACK LP SDP >
-shape	shape mode < RECTANGLE POLYGON >
-use_stitch	use stitch to avoid conflict
-gen_stitch	generate stitch candidate
-weight_stitch	weight of stitch
-thread_num	an integer indicating maximum thread number
-verbose	toggle controlling screen messages
-dbg_comp_id	debug component id



Experimental Settings

- ▶ Triple Patterning Lithography
- ▶ Conducted on modified ISCAS benchmarks from [Yu+,ICCAD'13]
- ▶ Coloring distance: $120nm$ for the first ten cases and $100nm$ for the last five cases.



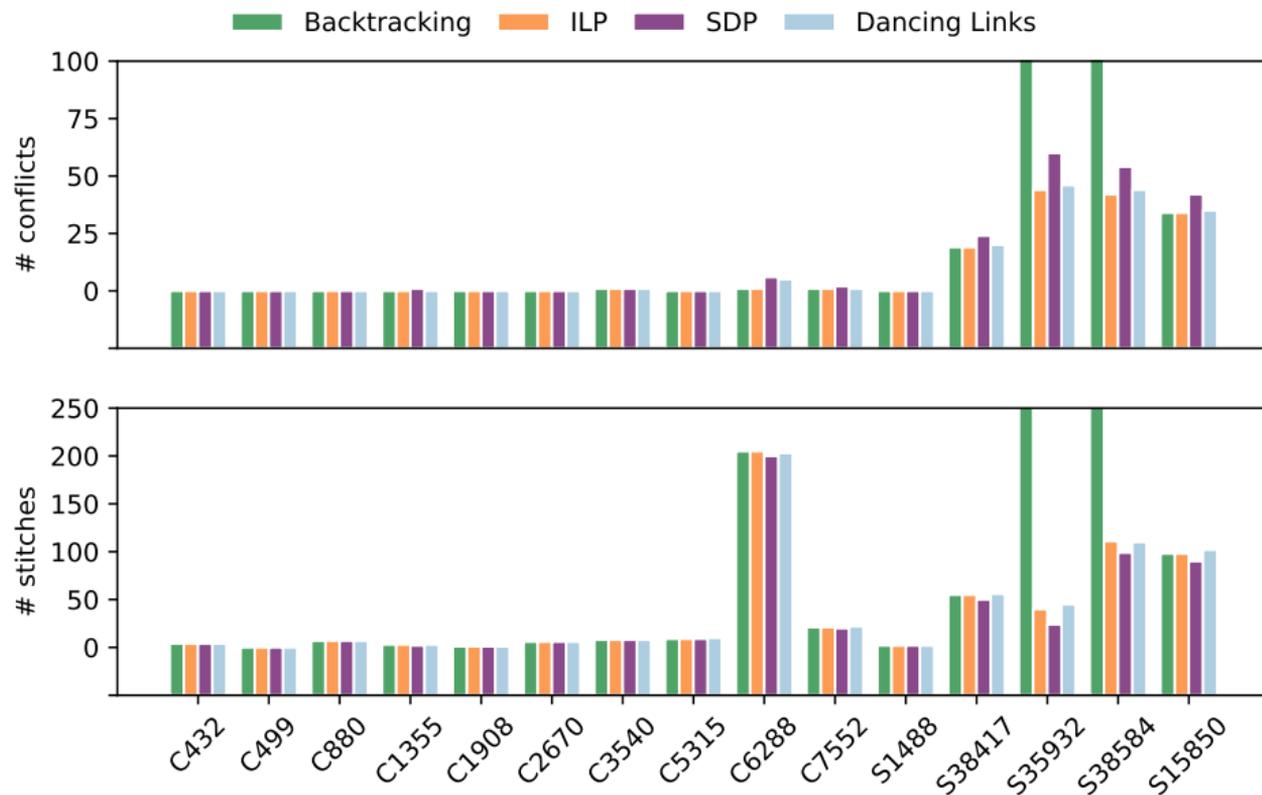
Experimental Results

(a) total_c1, TPLD, SDP coloring process.

(b) total_c2, TPLD, SDP coloring process.



Experimental Results – Quality



Experimental Results – Runtime



Quality and Runtime Tradeoffs

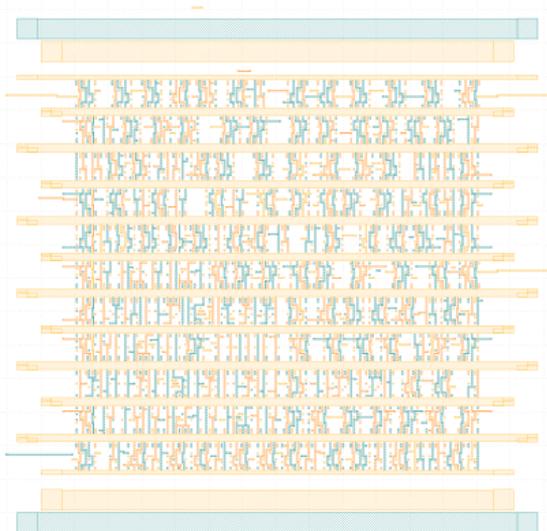
	Quality	Efficiency
Backtracking	★ ★ ★ ★ ★	★
ILP	★ ★ ★ ★ ★	★ ★
SDP	★ ★ ★	★ ★ ★ ★
Dancing Links	★ ★ ★ ★	★ ★ ★ ★ ★



Conclusion

Open-source layout decomposition framework

- ▶ Four layout decomposition solvers;
- ▶ Four graph simplification strategies;
- ▶ Multithreads, stitch insertion supported and shape frinedly.



Future Work

- ▶ Efficiency: hardware acceleration.
- ▶ Quality: post refinement.



Thank You



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